
# EBA & EBA/RF & DZ Series Batch Type Vacuum Coating System

## System Summary

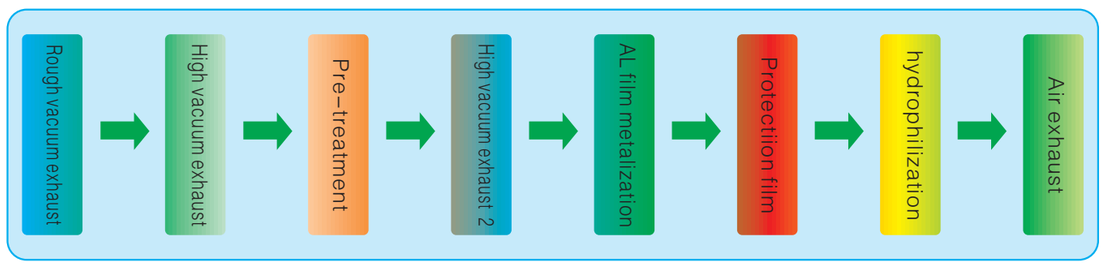
- This equipment, employing vertical double door open mechanism is applied to deposit Al reflection film and superposite SIOx protection film on the reflection board of automotive lighting parts, and decoration.

## Appliance

- Perform film metaliation on the PC,BMC,ABS metal materials;

## Features

- Adopt vertical double door open mechanism, tight compact;
- Each door is equipped with a set of 6–axis/8–axis self–revolution mechanism, a set of eveporation power, a set of superposition power. One door is performing film metalization, the other door can unload test part,install Al material.
- PLC control and touch screen interface, can realize full–automatic operation, easy operation.
- Advanced production process control program, high quality of film metalization.






# ULVAC Orient(Chengdu)Co.,Ltd

## Technical Parameters

| Item | EBA–2000C | EBA–2000HC |
|---|---|---|
| 1. Vacuum room & door | Vertical cylinderical type, double door | |
| 2. Internal cavity size | Φ1600mm*H1500mm | Φ1600mm*H1200mm |
| 3. Cycle time (unloaded) | 15min/per cycle | |
| 4. Height of effective film deposition area | H1200mm | H1700mm |
| 5. Self–resolution mechanism | 6–axis/8–axis | |
| 6. Metailization method | Resistance heating | |
| 7. Superpositon method | DC plasma polymerization | |
| 8. Gas exhaust system | able to assemble domestic pump or imported pump | |
| 9. Cold trap (optional) | America polycold | |
| 10. Vacuum gauge | able to assemble domestic gauge or imported gauge | |
| 11.Power | about 105KVA | about 110KVA |
| 12. Cooling water | about 120L/min | |
| 13. Space layout | about W6.9m*D6.2m*H3.0m | about 6.9m*D6.9*H3.2m |

| Item | EBA–1200HC/RF | EBA–2000C/RF | EBA–2000HC/RF |
|---|---|---|---|
| 1. Vacuum room & door | Vertical cylinderical type, double door | | |
| 2. Internal cavity size | Φ1200mm × H1300mm | Φ1600mm × H1500mm | Φ1600mm × H2000mm |
| 3. Cycle time (unloaded) | 12min/per cycle | 15min/per cycle | |
| 4. Height of effective film deposition area | H1000mm | H1200mm | H1700mm |
| 5. Self–resolution mechanism | 5–axis | 6–axis/8–axis | |
| 6. Metailization method | Resistance heating | | |
| 7. Superpositon method | RF plasma polymerization | | |
| 8. Gas exhaust system | able to assemble domestic pump or imported pump | | |
| 9. Cold trap (optional) | America polycold | | |
| 10. Vacuum gauge | able to assemble domestic gauge or imported | | |
| 11.Power | about 96KVA | | about 101KVA |
| 12. Cooling water | about 120L/min | | |
| 13. Space layout | about W4.9m × D5.8m × H3.0m | about W 6.9m × D6.2m × 2.9m | about W 6.9m × D6.9 × 3.2m |

| DZ–850 | |
|---|---|
| Item | Technical Parameters |
| 1.Vacuum room & door | Vertical cylinderical type, double door |
| 2. Internal cavity size | Φ940mm × H1900mm |
| 3. Cycle time (unloaded) | 420S/per cycle |
| 4. Effective film deposition area | Φ850mm × H1700mm |
| 5. Self–resolution mechanism | 1–axis( Max.self–revolution diameter 850mm) |
| 6. Metailization method | Resistance heating |
| 7. Superpositon method | RF plasma polymerization |
| 8. Gas exhaust system | able to assemble domestic pump or imported pump |
| 9. Cold trap (optional) | America polycold |
| 10. Vacuum gauge | able to assemble domestic gauge or imported gauge |
| 11.Space layout | about W4.2m × D6.2m × H2.9m |
| 12. Power | about 88KVA |
| 13. Cooling water | about 111L/min |